

0160-0193-0 PCT

#11118

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Hiroshi IKEDA, et al.

GAU:

1754

SERIAL NO: 09/463,961

EXAMINER: T. VANOY

FILED:

May 25, 2000

RCE FILED: HEREWITH

FOR:

METHOD AND APPARATUS FOR PROCESSING EXHAUST GAS OF SEMICONDUCTOR

FABRICATION

REQUEST FOR EXTENSION OF TIME UNDER 37 C.F.R. 1.136

ASSISTANT COMMISSIONER FOR PATENTS WASHINGTON, D.C. 20231

SIR:

It is hereby requested that a one month extension of time be granted to August 21, 2002 for	
filing a response to the Official Action dated:	
responding to the requirements in the Notice of Allowability dated:	
filing the Formal Drawings. The Issue Fee due	has been timely filed.
responding to the Notice to File Missing Parts of Application dated:	
filing a Notice of Appeal. A timely response to the final rejection, due	has been filed.
■ filing an Appeal Brief. A Request for Continued Examination (RCE) is being filed in lieu of the Appeal Brief.	
Applicant claims small entity status. See 37 CFR 1.27. Therefore, the fee amount shown below is reduced by one-half	

The required fee of \$110.00 is enclosed herewith by check and any further charges may be made against the Attorney of

Record's Deposit Account No. 15-0030. A duplicate copy of this sheet is enclosed.

Respectfully Submitted,

OBLON, SPIVAK, McCLELLAND,

MAIER & NEUSTADT, P.C.

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(OSMMN 10/01)

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